

Tokyo Electron's History

Tokyo Electron continues to evolve, incorporating new technologies and concepts in response to the changing times with a focus on the semiconductor production equipment field.

Founding Era

- 1963 Tokyo Electron Laboratories, Inc. (TEL) established and registered with a capital of five million yen.
- 1964 Starts importing and selling diffusion furnaces manufactured by Thermco Products Corp., taking its first step into the semiconductor production equipment import business.
- 1965 Concludes an agency agreement with Fairchild Semiconductor Corp. to sell Fairchild's IC testers in Japan.
- 1967 Establishes Pan Electron Inc. to start selling Fairchild's ICs.



Major Business Transformation

- 1968 TEL-Thermco Engineering Co., Ltd. (TEL-Thermco) established as a joint venture with Thermco Products Corp. and starts producing diffusion furnaces in Japan.
- 1972 Tokyo Process Development Inc. established and starts import and sale of analysis equipment. TEL headquarters moved to the Meiho Building in Shinjuku, Tokyo.
- 1975 Withdraws from production and export of consumer electronic goods, such as car radios and calculators, which accounted for 60% of sales.
- 1976 TEL-Thermco develops the world's first high-pressure oxidation system.



Manufacturing Functions Reinforced

- 1978 Tokyo Electron Laboratories, Inc. renamed Tokyo Electron Limited.
- 1980 Listed on the second section of the Tokyo Stock Exchange (TSE).
- 1981 TEL-GenRad Ltd. established and starts production of in-circuit board testers in Japan.
- 1983 TEL-LAM Ltd., established as a joint venture with U.S.-based Lam Research Corp., and starts production of etch systems in Japan.
- 1984 Listed on the first section of the Tokyo Stock Exchange.
- 1986 Central Research Laboratory facilities in Yamanashi Prefecture completed.



In-house Production Expanded

- 1988 TEL-Thermco Engineering Co. Ltd. purchased from Thermco Products Corp. and turned into 100%-owned subsidiary.
- 1989 Starts shipment of the CLEAN TRACK MARK-V, coater/developers.
- 1990 Makes a full-scale entry into the LCD production equipment market.



Era of Globalization

- 1993 Tokyo Electron FE Korea Limited (currently Tokyo Electron Korea Ltd.) established.
- 1994 Tokyo Electron Europe Limited established. Standards, Environment, & Safety Center (currently Environment, Health & Safety Center) established.
- 1996 Tokyo Electron America, Inc.'s new headquarters building and training center completed.
- 1997 Tokyo Electron Tohoku Limited's Sagami Plant becomes the first ISO14001-certified TEL Group company (all plants are subsequently acquiring ISO14001 certification).
- 1999 Receives TSE's Fourth Annual Award for Excellence in Disclosure.
- 2000 Semiconductor Equipment and Materials International (SEMI), an international industry organization, creates the SEMI Akira Inoue Award for Outstanding Achievement in honor of the environmental activities in the semiconductor industry of the late Tokyo Electron Ltd. Chairman Akira Inoue.



Starts Publication of the TEL Group's Environmental Report.

- 2001 Establishes a new corporate message "PEOPLE. TECHNOLOGY. COMMITMENT."

Striving for New Growth

- 2003 Receives the Japanese Prime Minister's Award for its industry-academia-government cooperative development of a large-diameter, high-density plasma processing system.
- 2005 Receives TSE's 10th Disclosure Award (for the second time after 1999).
- 2006 Establishes TEL Values.
- 2007 Establishes TEL UNIVERSITY as an internal educational institution to provide employee training and education.
- 2009 Concludes an agency agreement with Oerlikon Solar Ltd. to sell PV cell production equipment in the Asian and Oceanian regions.

